

Integrated Modulator I

Class: Integrated Photonic Devices

Time: Fri. 8:00am ~ 11:00am.

Classroom: 資電206

Lecturer: Prof. 李明昌(Ming-Chang Lee)

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Basic Operation Characteristic of Modulators

(1) Modulation Depth

$$\eta = \frac{(I_0 - I)}{I_0} \quad (\text{Decrease Intensity}) \longrightarrow \text{Type I}$$

I : the transmitted intensity

I_0 : the intensity without operation

$$\eta = \frac{(I - I_0)}{I_m} \quad (\text{Increase Intensity}) \longrightarrow \text{Type II}$$

I_m : the transmitted intensity with maximum signal

Therefore,

Extinction Ratio

$$\eta_{\max} = \frac{(I_0 - I_m)}{I_0} \quad \text{for } I_m \leq I_0 \quad (\text{Type I})$$

$$\eta_{\max} = \frac{(I_m - I_0)}{I_m} \quad \text{for } I_m \geq I_0 \quad (\text{Type II})$$

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Basic Operation Characteristic of Modulators

If the modulation of intensity is related to phase modulation such as MZI, the modulation depth

$$\eta = \sin^2\left(\frac{\Delta\phi}{2}\right) \quad \Delta\phi \text{ is the phase change}$$

If the modulation is on frequency, the modulation depth is

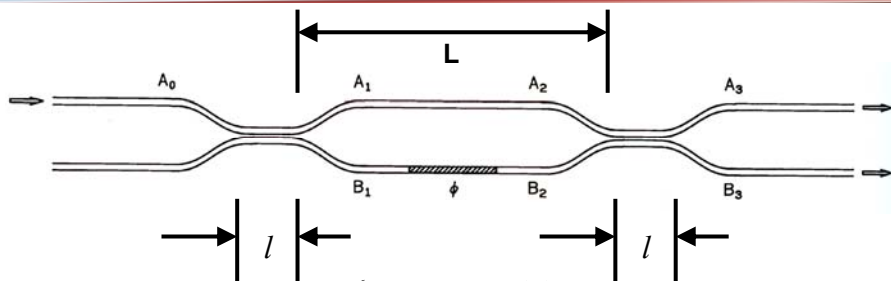
$$D_{\max} = \frac{|f_m - f_0|}{f_0} \quad \begin{array}{l} f_0 : \text{optical carrier frequency} \\ f_m : \text{shifted optical frequency} \end{array}$$

(2) Bandwidth

$$T = \frac{2\pi}{\Delta f} \quad \begin{array}{l} T : \text{minimal switching time} \\ \Delta f : \text{bandwidth (3dB)} \end{array}$$

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Guided-Wave Mach-Zehnder Interferometer



$$\begin{cases} |A_3|^2 = |A_0|^2 \sin^2\left(\frac{\phi}{2}\right) \\ |B_3|^2 = |A_0|^2 \cos^2\left(\frac{\phi}{2}\right) \end{cases}$$

If ϕ is slightly modulated with $\delta\phi$

$$\begin{cases} |A_3|^2 \cong |A_0|^2 \left(\frac{\delta\phi}{2}\right)^2 \\ |B_3|^2 = |A_0|^2 \end{cases}$$

It is not linear modulation!

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Basic Operation Characteristic of Modulators

(3) Insertion Loss (Optical)

$$L_i = 10 \cdot \log\left(\frac{I_i}{I_0}\right) \quad (\text{Type I})$$

I_0 : the intensity without operation

I_i : Input light intensity

$$L_i = 10 \cdot \log\left(\frac{I_i}{I_m}\right) \quad (\text{Type II})$$

I_m : the transmitted intensity with maximum signal

(4) Power Consumption (Electrical)

$$\frac{P}{\Delta f}$$

Signal Power (Electrical) ← P
Bandwidth ← Δf

In most cases of modulators, the required drive power increases with modulation frequency.
Most of power is consumed during transient time

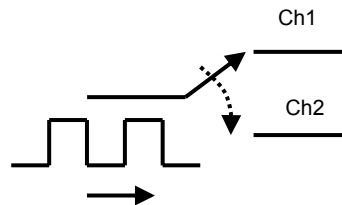
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Basic Operation Characteristic of Modulators

(5) Isolation (Crosstalk for switch)

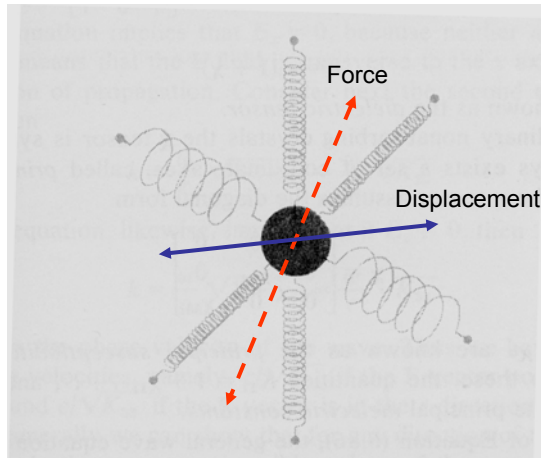
$$\text{Isolation [dB]} = 10 \cdot \log\left(\frac{I_2}{I_1}\right)$$

As channel 1 is on but channel 2 is off



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Linear Anisotropic Medium



Anisotropic Materials

ϵ : tensor

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Linear Anisotropic Medium

In a *linear* anisotropic medium, the electric displacement can be expressed in a matrix form

$$\begin{bmatrix} D_x \\ D_y \\ D_z \end{bmatrix} = \begin{bmatrix} \epsilon_{11} & \epsilon_{12} & \epsilon_{13} \\ \epsilon_{21} & \epsilon_{22} & \epsilon_{23} \\ \epsilon_{31} & \epsilon_{32} & \epsilon_{33} \end{bmatrix} \begin{bmatrix} E_x \\ E_y \\ E_z \end{bmatrix} \quad (\mathbf{D} = \boldsymbol{\epsilon} \cdot \mathbf{E})$$

If the material is nonmagnetic and lossless, the matrix $\boldsymbol{\epsilon}$ is symmetric and can be diagonalized with real eigenvalues. And the eigenvectors are also real. Therefore,

$$\begin{aligned} \boldsymbol{\epsilon} &\rightarrow \boldsymbol{\epsilon}' \\ \text{and} \\ x, y, z &\rightarrow x', y', z' \end{aligned} \quad \begin{bmatrix} D_{x'} \\ D_{y'} \\ D_{z'} \end{bmatrix} = \begin{bmatrix} \epsilon_{x'} & 0 & 0 \\ 0 & \epsilon_{y'} & 0 \\ 0 & 0 & \epsilon_{z'} \end{bmatrix} \begin{bmatrix} E_{x'} \\ E_{y'} \\ E_{z'} \end{bmatrix}$$

The diagonalization is correspondent to transferring the initial coordinate system to the principle coordinate system

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Linear Anisotropic Medium

The energy stored in the nonmagnetic, lossless medium is

$$U_e = \frac{1}{2} \mathbf{E} \cdot \mathbf{D} = \frac{1}{2} \sum_{i,j} E_i \epsilon_{ij} E_j$$

If \mathbf{E} and \mathbf{D} are presented according to the principle coordinate system

$$2U_e = \frac{D_x^2}{\epsilon_x} + \frac{D_y^2}{\epsilon_y} + \frac{D_z^2}{\epsilon_z} \quad \text{Replace } \frac{\epsilon_0 \mathbf{D}}{\sqrt{2U_e}} = (x, y, z)$$

$$\longrightarrow \frac{x^2}{n_x^2} + \frac{y^2}{n_y^2} + \frac{z^2}{n_z^2} = 1 \quad (\text{Index Ellipsoid}) \quad \text{where } n_i = \sqrt{\frac{\epsilon_i}{\epsilon_0}}$$

A general expression of index ellipsoid (not in the principle coordinate system but in crystal symmetry coordinate) is

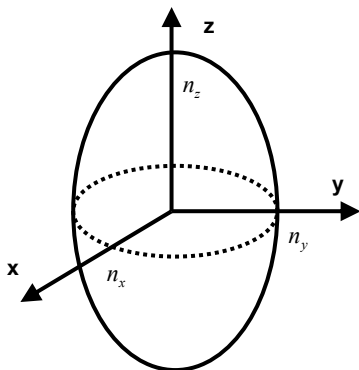
$$\eta_1 (x')^2 + \eta_2 (y')^2 + \eta_3 (z')^2 + 2\eta_4 y' z' + 2\eta_5 x' z' + 2\eta_6 x' y' = 1$$

$$\text{In fact } \boldsymbol{\eta} = \left(\frac{\boldsymbol{\epsilon}}{\epsilon_0} \right)^{-1} \equiv \frac{1}{\mathbf{n}^2}$$

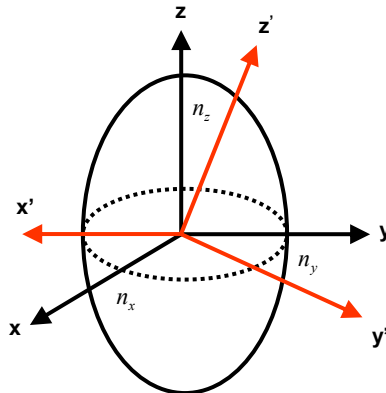
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Linear Anisotropic Medium

Index Ellipsoid
(Principle Coordinate)



Index Ellipsoid
(Other Coordinate)

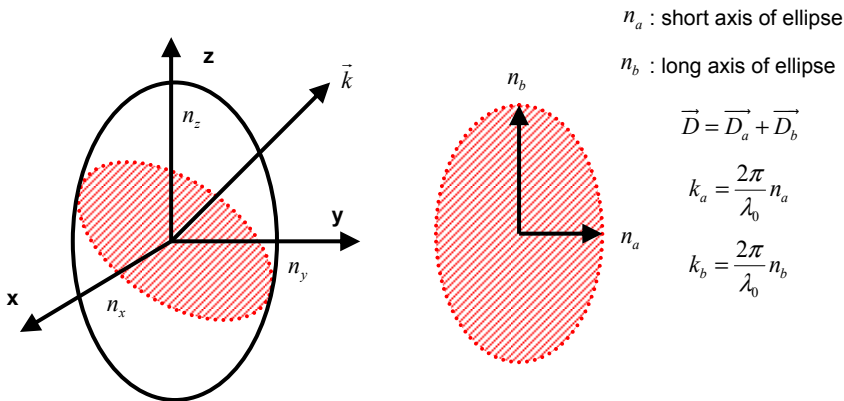


If $n_x \neq n_y \neq n_z \longrightarrow$ Biaxial crystals

If $n_x = n_y \neq n_z \longrightarrow$ Uniaxial crystals

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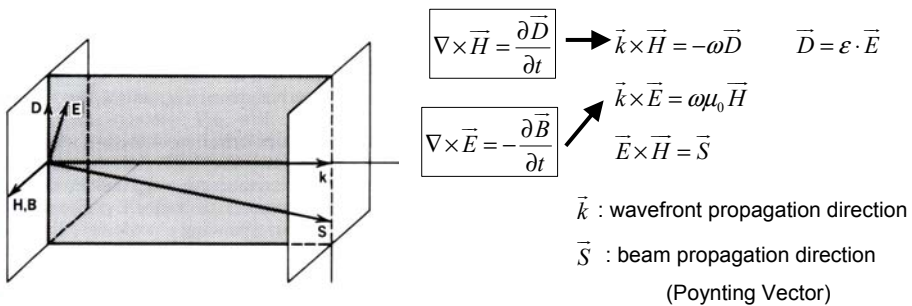
Linear Anisotropic Medium



- The wave numbers of two orthogonal displacement vectors are not the same
 - Optical axis: How to choose the direction of \vec{k} such that $n_a = n_b$ (circular cross section) (no birefringence)
- Uniaxial: single optical axis \longrightarrow principle axis
 biaxial: two optical axes

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Wavefront Propagation Direction vs. Beam Direction (not along optical axis)



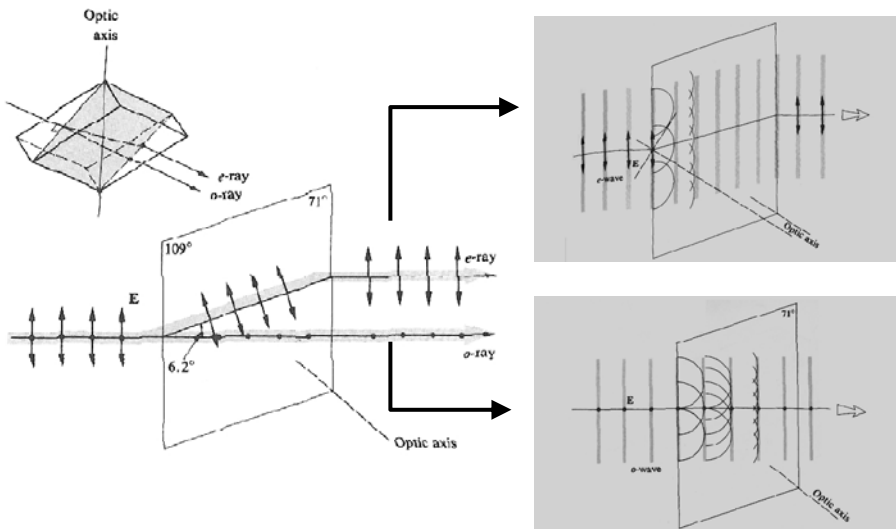
$\vec{k}, \vec{H}, \vec{D}$ are mutual orthogonal

$\vec{S}, \vec{H}, \vec{E}$ are mutual orthogonal

But \vec{E}, \vec{k} are not perpendicular and \vec{S}, \vec{k} are not parallel

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Wavefront Propagation Direction vs. Beam Direction (not along optical axis)



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Index, k-vector and s-vector for a normal incident

- step 1: Draw the index ellipsoid and label principle axes and indices
- step 2: Draw crystal cut
- step 3: Draw the electric displacement plane (perpendicular to the incident k vector)
- step 4: Determine two orthogonal D vectors (long axis and short axis) and the correspondent indices
- step 5: Decompose the beam into these two components
- step 6: The transmitted angles of these two s vectors are determined by the dielectric tensor

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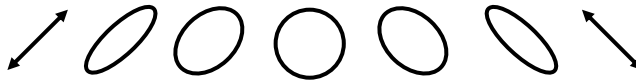
Propagation along a Principle Axis

When the wave propagates along one of the principle axes, say z. Then the field can be decomposed into two normal modes

$$E = \hat{x}E_x \exp(jk_x z - j\omega t) + \hat{y}E_y \exp(jk_y z - j\omega t) \\ = \left\{ \hat{x}E_x + \hat{y}E_y \exp[j(k_y - k_x)z] \right\} \exp(jk_x z - j\omega t)$$

- If it is originally linearly polarized along one of the principle axes, it remains linearly polarized in the same direction
- If it is originally linearly polarized at an angle $\theta = \tan^{-1}(\frac{E_y}{E_x})$ with respect to the x-axis, its polarization state varies periodically along z with a period

$$\frac{2\pi}{|k_x - k_y|}$$



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Electro-Optic Effects

The electro-optic effects are traditionally defined in terms of the changes in the elements of the relative impermeability tensor η

$$\eta_{\alpha}(E_0) = \eta_{\alpha}^{(1)} + \Delta\eta_{\alpha}(E_0) = \eta_{\alpha}^{(1)} + \sum_k r_{\alpha k} E_{0k} + \sum_{k,l} s_{\alpha kl} E_{0k} E_{0l} + \dots$$

$r_{\alpha k}$: Pockels coefficient (linear electro-optic)

where

$s_{\alpha kl}$: Kerr coefficient (quadratic electro-optic)

- The Pockels effect does not exist in a material with inversion symmetry, which is called a centrosymmetric material.
- The Kerr effect exists in all materials

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Pockels Effects

For the Pockels effect,

$$\Delta\eta_{\alpha}(E_0) = \sum_k r_{\alpha k} E_{0k}$$

Which can be written explicitly in the following matrix form

$$\begin{bmatrix} \Delta\eta_1 \\ \Delta\eta_2 \\ \Delta\eta_3 \\ \Delta\eta_4 \\ \Delta\eta_5 \\ \Delta\eta_6 \end{bmatrix} = \begin{bmatrix} r_{11} & r_{12} & r_{13} \\ r_{21} & r_{22} & r_{23} \\ r_{31} & r_{32} & r_{33} \\ r_{41} & r_{42} & r_{43} \\ r_{51} & r_{52} & r_{53} \\ r_{61} & r_{62} & r_{63} \end{bmatrix} \begin{bmatrix} E_{0x} \\ E_{0y} \\ E_{0z} \end{bmatrix}$$

- For a noncentrosymmetric material, the number of nonvanishing independent elements in its $r_{\alpha k}$ matrix is generally reduced by its symmetry

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Matrix Form of Pockels Coefficients

Table 5.1: Matrix form of Pockels coefficients for noncentrosymmetric point groups*

Table 5.1: (Continued)											
Triclinic	1	$\begin{bmatrix} r_{11} & r_{12} & r_{13} \\ r_{21} & r_{22} & r_{23} \\ r_{31} & r_{32} & r_{33} \\ r_{41} & r_{42} & r_{43} \\ r_{51} & r_{52} & r_{53} \\ r_{61} & r_{62} & r_{63} \end{bmatrix}$		Trigonal	3	$\begin{bmatrix} r_{11} & -r_{22} & r_{33} \\ -r_{11} & r_{22} & r_{33} \\ 0 & 0 & r_{33} \\ r_{41} & r_{51} & 0 \\ r_{51} & -r_{41} & 0 \\ -r_{22} & -r_{33} & 0 \end{bmatrix}$					
Monoclinic	2	$\begin{bmatrix} 0 & r_{21} & 0 \\ 0 & r_{22} & 0 \\ 0 & r_{23} & 0 \\ r_{41} & 0 & r_{43} \\ 0 & r_{52} & 0 \\ r_{51} & 0 & r_{63} \end{bmatrix}$	m	$\begin{bmatrix} r_{11} & 0 & r_{13} \\ r_{21} & 0 & r_{23} \\ r_{31} & 0 & r_{33} \\ r_{41} & 0 & r_{43} \\ 0 & r_{51} & r_{53} \\ 0 & r_{62} & 0 \end{bmatrix}$	32	$\begin{bmatrix} r_{11} & 0 & 0 \\ -r_{11} & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & -r_{41} & 0 \\ 0 & -r_{11} & 0 \end{bmatrix}$	3m	$\begin{bmatrix} 0 & -r_{22} & r_{33} \\ 0 & r_{22} & r_{33} \\ 0 & 0 & r_{33} \\ 0 & 0 & r_{51} & 0 \\ r_{51} & 0 & 0 \\ -r_{22} & 0 & 0 \end{bmatrix}$	LiNb ₃		
Orthorhombic	222	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & r_{52} & 0 \\ 0 & 0 & r_{63} \end{bmatrix}$	mm2	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & r_{23} \\ 0 & 0 & r_{33} \\ 0 & r_{42} & 0 \\ r_{51} & 0 & 0 \\ 0 & 0 & 0 \end{bmatrix}$	Hexagonal	6	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & r_{13} \\ 0 & 0 & r_{33} \\ r_{41} & r_{51} & 0 \\ r_{51} & -r_{41} & 0 \\ 0 & 0 & 0 \end{bmatrix}$	$\bar{6}$	$\begin{bmatrix} r_{11} & -r_{22} & 0 \\ -r_{11} & r_{22} & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ -r_{22} & -r_{11} & 0 \end{bmatrix}$		
Tetragonal	4	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & -r_{13} \\ 0 & 0 & 0 \\ r_{41} & r_{51} & 0 \\ r_{51} & -r_{41} & 0 \\ 0 & 0 & 0 \end{bmatrix}$	$\bar{4}$	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & -r_{13} \\ 0 & 0 & 0 \\ r_{41} & -r_{51} & 0 \\ r_{51} & r_{41} & 0 \\ 0 & 0 & r_{63} \end{bmatrix}$	622	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & -r_{41} & 0 \\ 0 & 0 & 0 \end{bmatrix}$	6mm	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & r_{13} \\ 0 & 0 & r_{33} \\ 0 & r_{51} & 0 \\ r_{51} & 0 & 0 \\ 0 & 0 & 0 \end{bmatrix}$	$\bar{6}m2$	$\begin{bmatrix} 0 & -r_{22} & 0 \\ 0 & r_{22} & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ -r_{22} & 0 & 0 \end{bmatrix}$	
422	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & -r_{41} & 0 \\ 0 & 0 & 0 \end{bmatrix}$	4mm	$\begin{bmatrix} 0 & 0 & r_{13} \\ 0 & 0 & r_{13} \\ 0 & 0 & r_{33} \\ 0 & r_{51} & 0 \\ r_{51} & 0 & 0 \\ 0 & 0 & 0 \end{bmatrix}$	$\bar{4}2m$	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & r_{41} & 0 \\ 0 & 0 & r_{63} \end{bmatrix}$	Cubic	432	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \end{bmatrix}$	23 and $\bar{4}3m$	$\begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & r_{41} & 0 \\ 0 & 0 & r_{41} \end{bmatrix}$	III-V

Electro-Optic Effects

The original diagonalized dielectric tensors therefore changed due to the electro-optic effects

$$\boldsymbol{\epsilon}^{(1)} = \begin{bmatrix} \epsilon_x^{(1)} & 0 & 0 \\ 0 & \epsilon_y^{(1)} & 0 \\ 0 & 0 & \epsilon_z^{(1)} \end{bmatrix} \xrightarrow{\text{Electro-Optics}} \boldsymbol{\epsilon} = \begin{bmatrix} \epsilon_x^{(1)} + \Delta\epsilon_{xx} & \Delta\epsilon_{xy} & \Delta\epsilon_{xz} \\ \Delta\epsilon_{yx} & \epsilon_y^{(1)} + \Delta\epsilon_{yy} & \Delta\epsilon_{yz} \\ \Delta\epsilon_{zx} & \Delta\epsilon_{zy} & \epsilon_z^{(1)} + \Delta\epsilon_{zz} \end{bmatrix}$$

Diagonalized

$$\text{where } \frac{\Delta\epsilon_{ij}}{\epsilon_0} \simeq -\frac{\Delta\eta_{ij}}{\eta_i^{(1)}\eta_j^{(1)}} \quad \text{since } \epsilon_i^{(1)} \gg |\Delta\epsilon_{i,j}|$$

- With electro-optic effects, not only the refractive index but also the principle axes are changed

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LiNbO₃ (3m) Electro-Optics

$$(1). E_{0x} = E_{0y} = 0, \quad E_{0z} \neq 0$$

$$\Delta\eta_1 = r_{13}E_{0z} \quad \Delta\eta_2 = r_{13}E_{0z} \quad \Delta\eta_3 = r_{33}E_{0z}$$

The index ellipsoid becomes

$$\left(\frac{1}{n_0^2} + r_{13}E_{0z}\right)x^2 + \left(\frac{1}{n_0^2} + r_{13}E_{0z}\right)y^2 + \left(\frac{1}{n_e^2} + r_{33}E_{0z}\right)z^2 = 1$$

$$\boldsymbol{\epsilon} = \epsilon_0 \begin{bmatrix} n_0^2 - n_0^4 r_{13} E_{0z} & 0 & 0 \\ 0 & n_0^2 - n_0^4 r_{13} E_{0z} & 0 \\ 0 & 0 & n_e^2 - n_e^4 r_{33} E_{0z} \end{bmatrix}$$

$$\begin{bmatrix} \Delta\eta_1 \\ \Delta\eta_2 \\ \Delta\eta_3 \\ \Delta\eta_4 \\ \Delta\eta_5 \\ \Delta\eta_6 \end{bmatrix} = \begin{bmatrix} 0 & -r_{22} & r_{13} \\ 0 & r_{22} & r_{13} \\ 0 & 0 & r_{33} \\ 0 & r_{51} & 0 \\ r_{51} & 0 & 0 \\ -r_{22} & 0 & 0 \end{bmatrix} \begin{bmatrix} E_{0x} \\ E_{0y} \\ E_{0z} \end{bmatrix}$$

- The principle axes are not rotated. The crystal remains uniaxial with the same optical axis
- The indices of refraction are changed

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KDP (KH₂PO₄) ($\bar{4}2m$)

The crystal symmetry of KDP is $\bar{4}2m$

$$\begin{bmatrix} \Delta\eta_1 \\ \Delta\eta_2 \\ \Delta\eta_3 \\ \Delta\eta_4 \\ \Delta\eta_5 \\ \Delta\eta_6 \end{bmatrix} = \begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & r_{41} & 0 \\ 0 & 0 & r_{63} \end{bmatrix} \begin{bmatrix} E_{0x} \\ E_{0y} \\ E_{0z} \end{bmatrix}$$

Now we consider the case when the field is applied along the z-axis:

$$E_{0x} = E_{0y} = 0 \quad \text{and} \quad E_{0z} \neq 0$$

$$\frac{x^2 + y^2}{n_o^2} + \frac{z^2}{n_e^2} = 1 \quad \longrightarrow \quad \frac{x^2 + y^2}{n_o^2} + \frac{z^2}{n_e^2} + 2r_{61}E_{0z}xy = 1$$

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KDP (KH₂PO₄)

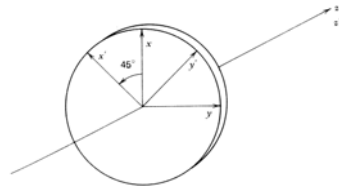
In dielectric matrix representation,

$$\boldsymbol{\epsilon}' = \boldsymbol{\epsilon}_0 \begin{bmatrix} n_o^2 & -n_o^4 r_{63} E_{0z} & 0 \\ -n_o^4 r_{63} E_{0z} & n_o^2 & 0 \\ 0 & 0 & n_e^2 \end{bmatrix}$$

$$(x, y, z) \rightarrow (x', y', z') \quad \text{and} \quad (n_x, n_y, n_z) \rightarrow (n'_x, n'_y, n'_z)$$

where

$$\begin{pmatrix} x' \\ y' \\ z' \end{pmatrix} = \begin{pmatrix} \frac{1}{\sqrt{2}}(x+y) \\ \frac{1}{\sqrt{2}}(-x+y) \\ z \end{pmatrix} \quad \text{and} \quad \begin{pmatrix} n'_x \\ n'_y \\ n'_z \end{pmatrix} = \begin{pmatrix} n_o - \frac{n_o^3}{2} r_{63} E_{0z}^2 \\ n_o + \frac{n_o^3}{2} r_{63} E_{0z}^2 \\ n_e \end{pmatrix}$$



Uniaxial \longrightarrow Biaxial

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GaAs ($\bar{4}3m$)

For the III-V semiconductor with ($\bar{4}3m$) symmetry, since

$$n_x = n_y = n_z = n_0$$

The only nonvanishing Pockels coefficients are

$$\gamma_{41} = \gamma_{52} = \gamma_{63}$$

$$\begin{bmatrix} \Delta\eta_1 \\ \Delta\eta_2 \\ \Delta\eta_3 \\ \Delta\eta_4 \\ \Delta\eta_5 \\ \Delta\eta_6 \end{bmatrix} = \begin{bmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & 0 & 0 \\ r_{41} & 0 & 0 \\ 0 & r_{41} & 0 \\ 0 & 0 & r_{41} \end{bmatrix} \begin{bmatrix} E_{0x} \\ E_{0y} \\ E_{0z} \end{bmatrix}$$

We therefore consider only the case when the field is applied along the z-axis

$$E_{0x} = E_{0y} = 0 \quad \text{and} \quad E_{0z} \neq 0$$

Then we only have $\Delta\eta_6 = \gamma_{41}E_{0z}$

The index ellipsoid becomes

$$\frac{1}{n_0^2}x^2 + \frac{1}{n_0^2}y^2 + \frac{1}{n_0^2}z^2 + 2\gamma_{41}E_{0z}xy = 1$$

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GaAs ($\bar{4}3m$)

The dielectric permittivity tensor becomes

$$\epsilon = \epsilon_0 \begin{bmatrix} n_0^2 & -n_0^4 \gamma_{41} E_{0z} & 0 \\ -n_0^4 \gamma_{41} E_{0z} & n_0^2 & 0 \\ 0 & 0 & n_0^2 \end{bmatrix}$$

This results in the following new principle axes

$$\hat{x}' = \frac{1}{\sqrt{2}}(\hat{x} + \hat{y}) \quad \text{and} \quad \hat{y}' = \frac{1}{\sqrt{2}}(-\hat{x} + \hat{y}) \quad \text{and} \quad \hat{z}' = \hat{z}$$

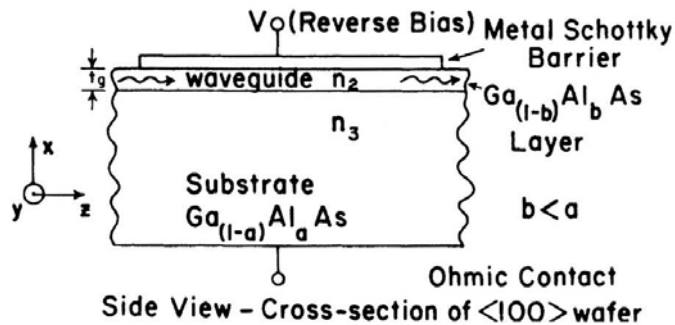
with

$$n_{x'} \approx n_0 - \frac{n_0^3}{2} \gamma_{41} E_{0z} \quad \text{and} \quad n_{y'} \approx n_0 + \frac{n_0^3}{2} \gamma_{41} E_{0z} \quad \text{and} \quad n_{z'} = n_0$$

Isotropic \longrightarrow Biaxial (Anisotropic)

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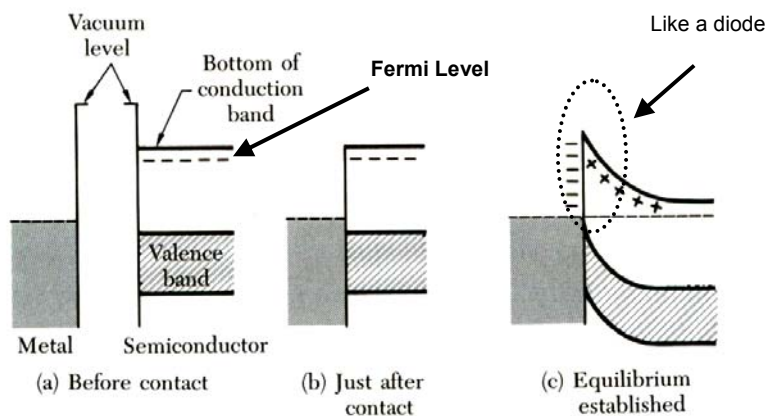
Single-Waveguide EO Modulators



- It can operate as either phase modulator, amplitude modulator, polarization modulator or optical switch
- Various materials such as LiNbO_3 , GaP , LiTaO_3 can be used.
- The metal contact forms a Schottky diode in the interface (for applying electric field)

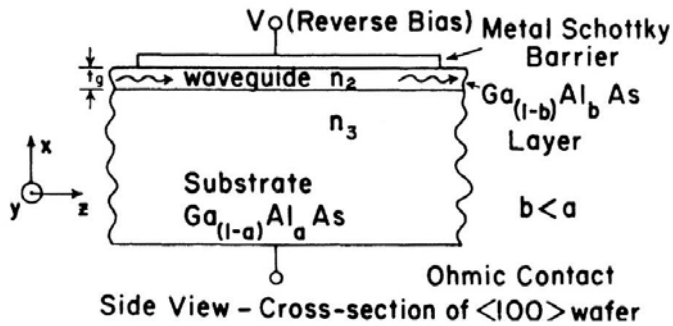
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Schottky Barrier



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Single-Waveguide EO Modulators



(1) Phase Modulation

$$\Delta n_{23} = n_2 - n_3 = \Delta n_{\text{chemical}} + \Delta n_{\text{CCR}} + \Delta n_{\text{EO}}$$

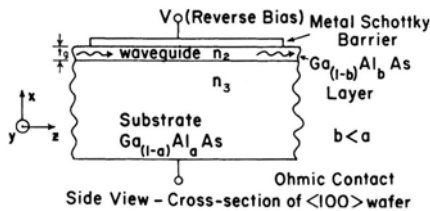
Material Index Contrast

Electro-Optic Effect

Concentration Reduction (if any)

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Single-Waveguide EO Modulators



Without Bias

The cut-off condition for single mode waveguide:

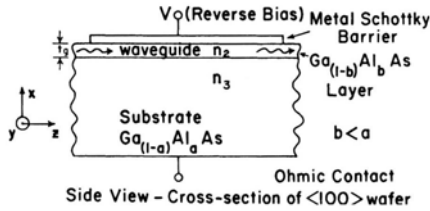
$$\frac{1}{32n_2} \left(\frac{\lambda_0}{t_g} \right)^2 < \Delta n_{\text{chemical}} + \Delta n_{\text{CCR}} < \frac{9}{32n_2} \left(\frac{\lambda_0}{t_g} \right)^2$$

When a voltage V is applied with reversed bias on the Schottky diode, the electric fields are built within the waveguide.

$$\Delta n_{\text{EO}} = n_2^3 r_{41} \frac{V}{2t_g} \quad (\text{TE-polarized in y-direction})$$

(There is no field-induced index change in TM waves)

Single-Waveguide EO Modulators



Therefore, the index change due to electric fields becomes

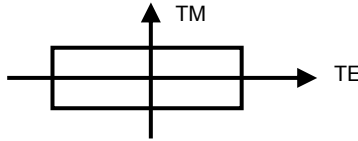
$$\Delta n = \frac{\Delta \beta}{k} = \frac{\Delta \beta \lambda_0}{2\pi}$$

(TE-polarized in y-direction)

The phase change produced by the electric field is given by

$$\Delta \phi_{EO} = \Delta \beta L = \frac{\pi}{\lambda_0} n_2^3 r_{41} \frac{VL}{t_g}$$

(2) Polarization Modulation

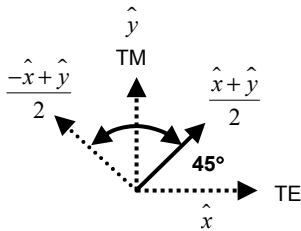


$$\Delta n_{TE} = n_2^3 r_{41} \frac{V}{2t_g}$$

$$\Delta n_{TM} = 0$$

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Single-Waveguide EO Modulators



$$\begin{aligned} E &= \hat{x}E_0 \exp(j\beta_{TE}z) + \hat{y}E_0 \exp(j\beta_{TM}z) \\ &= E_0 \exp(j\beta_{TM}z) \left\{ \hat{x} \exp(j\Delta\beta z) + \hat{y} \right\} \\ &= E_0 \exp(j\beta_{TM}z) \left\{ \hat{x} \exp\left(j \frac{\pi}{\lambda_0} n_2^3 r_{41} \frac{Vz}{t_g}\right) + \hat{y} \right\} \end{aligned}$$

(3) Intensity Modulation

- The index contrast is designed just around the cut-off condition of fundamental mode without bias.

$$\Delta n_{23} = \Delta n_{chemical} + \Delta n_{CCR} = \frac{1}{32n_2} \left(\frac{\lambda_0}{t_g} \right)^2$$

$$\Delta n_{EO} > 0 \quad \text{Transmitted}$$

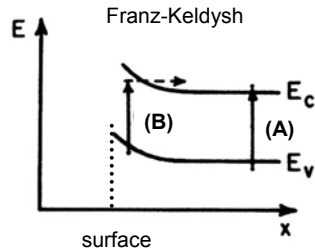
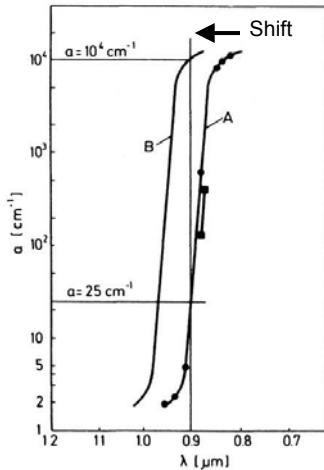
$$\Delta n_{EO} < 0 \quad \text{Radiated}$$

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Single-Waveguide EA Modulators

(4) Electro-Absorption Modulation

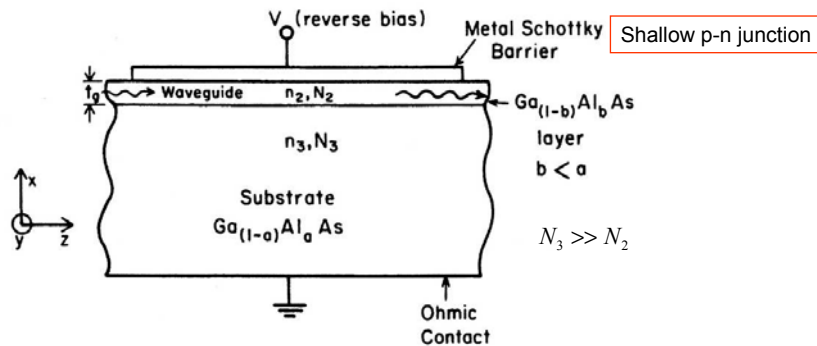
- Franz-Keldysh effect or Quantum Confined Stark effect (QCSE)



- The band edge shifts to long wavelength with electric bias
- Energy band bends significantly near surface

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Single-Waveguide EA Modulators



$N_3 \gg N_2 \rightarrow$ Reduce the resistance in the substrate and increase the depletion area in the waveguide

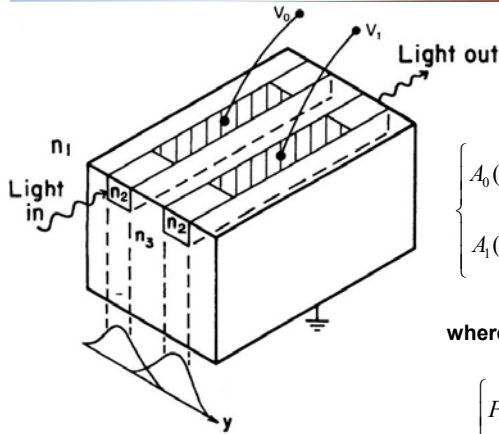
The effective change in bandgap energy ΔE is given by

$$\Delta E = \frac{3}{2} (m^*)^{-1/3} (q\hbar\psi)^{2/3}$$

m^* : effective mass ψ : applied field

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Dual-Channel Waveguide EO Modulators



Recall

$$A_0(0) = 1 \quad \text{and} \quad A_1(0) = 0$$

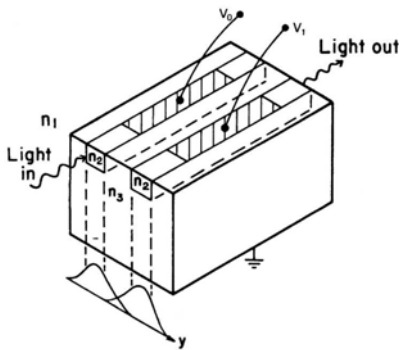
$$\begin{cases} A_0(z) = \left(\cos gz - j \frac{\Delta\beta}{2g} \sin gz \right) \exp \left[-j \left(\beta_0 - \frac{\Delta\beta}{2} \right) z \right] \\ A_1(z) = - \left(\frac{-j\kappa}{g} \sin gz \right) \exp \left[-j \left(\beta_1 + \frac{\Delta\beta}{2} \right) z \right] \end{cases}$$

where $\Delta\beta = \beta_0 - \beta_1$ and $g^2 \equiv \kappa^2 + \left(\frac{\Delta\beta}{2} \right)^2$

$$\begin{cases} P_0(z) = \cos^2(gz) - \left(\frac{\Delta\beta}{2} \right)^2 \frac{\sin^2(gz)}{g^2} \\ P_1(z) = \frac{\kappa^2}{g^2} \sin^2(gz) \end{cases}$$

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Dual-Channel Waveguide EO Modulators



when $\Delta\beta = 0$, 100% power is transferred if

$$\kappa L = \frac{\pi}{2} + m\pi \quad m = 0, 1, 2, \dots \quad (a)$$

When a modulating voltage is applied to produce a $\Delta\beta$, the coupling could be completely cancelled if

$$gL = \pi + m\pi \quad m = 0, 1, 2, \dots \quad (b)$$

Combine (a) and (b), it can be shown that the value of $\Delta\beta$ required for 100% modulation is given by

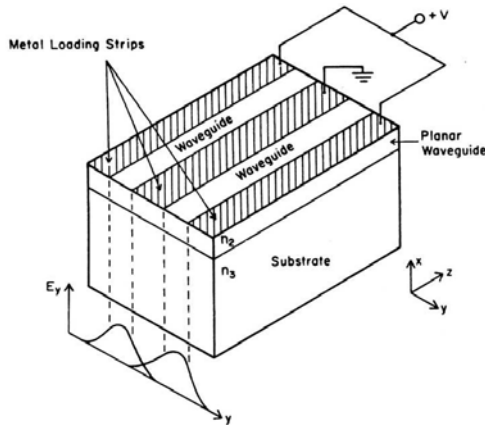
$$(\Delta\beta)L = \sqrt{3}\pi$$

The change in effective index needed for 100% modulation

$$\Delta n_g = \frac{\sqrt{3}\pi}{k_0 L}$$

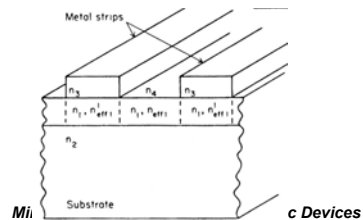
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Dual-Channel Waveguide EO Modulators

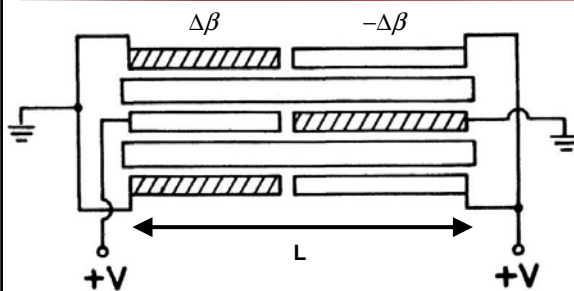


Three-electrode Dual-Channel Waveguide Modulators

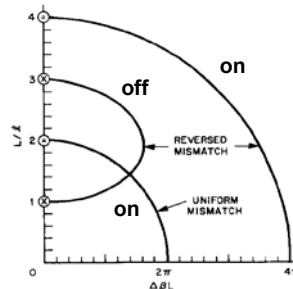
- Fabricated in GaAs
- A pair of strip-loaded waveguides
- Extinction Ratio: 13dB
- Applied Voltage: 35V
- 7-ns rise time
- The power-bandwidth ratio: 180mW/MHz



Dual-Channel Waveguide EO Modulators

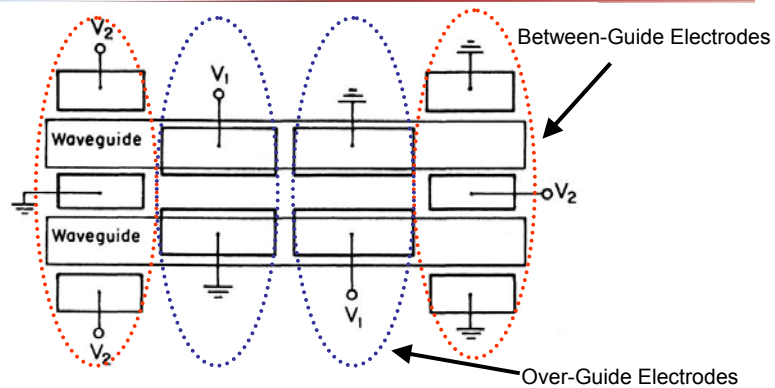


Split-Electrode Dual-Channel Waveguide Modulators



- 100% power transfer is insensitive to the waveguide length.
- The on and off states are controlled by $\Delta\beta$.
- It allows a maximum extinction ratio and a minimum crosstalk.
- The waveguide length
$$L > \frac{\pi}{2\kappa} = l$$

Dual-Channel Waveguide EO Modulators

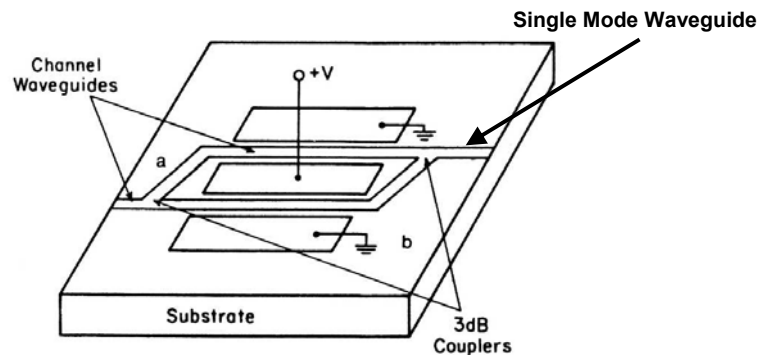


Polarization Insensitive Modulators

- Stepped $\Delta\beta$ reversal electrodes are both for TE and TM polarization

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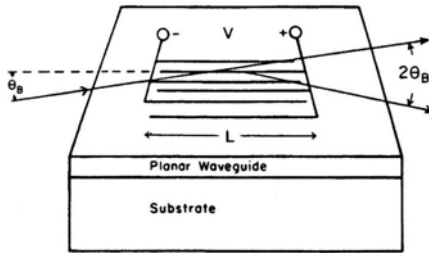
Mach-Zehnder Type Electro-Optic Modulators



- Ideally, the path lengths and guide characteristics are identical.
- The Y-branch is a perfect 3dB splitter.
- The input and output waveguides are single mode.
- The optical wave radiates as the phase difference is equal to π .

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Bragg-Effect EO Modulators



Suppose

$$2\pi\lambda_0 L \gg \Lambda^2 \quad (\text{thick grating})$$

The Bragg angle θ_B is given by

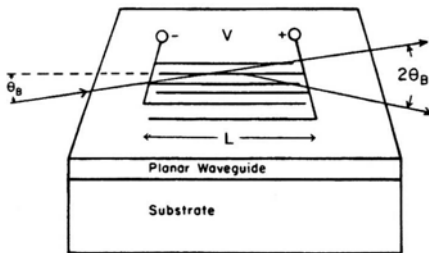
$$\sin \theta_B = \frac{\lambda_0}{2\Lambda n_g} \quad \Lambda: \text{Grating Space}$$

$$n_g = \frac{\beta}{k_0} \quad (\text{effective index})$$

- Index grating is patterned by a interlace, com-like, pair of electrodes
- The index difference is modulated by electro-optic effects
- The input angle of guided wave is aligned to the Bragg angle.
- The output wave is diffracted by $2\theta_B$ angle

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Bragg-Effect EO Modulators



If the input angle is deviated from the Bragg angle by $\Delta\theta_B$, the diffracted efficiency is reduced.

The 50%-reduction deviation angle is

$$\Delta\theta_B = \frac{2\Lambda}{L}$$

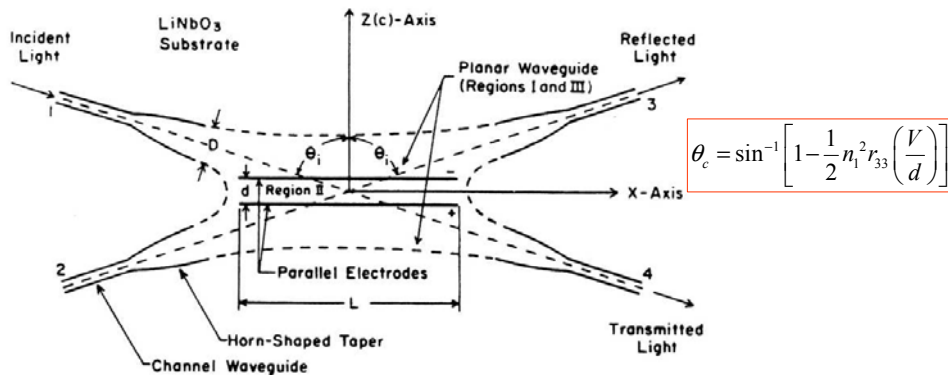
The intensity of light diffraction is dependent on the applied voltage, which is given by

$$\frac{I_{\text{diffracted}}}{I_{\text{transmitted}}} = \sin^2 VB \quad B: \text{constant dependent on waveguide}$$

- Demonstrated in ZnO, LiTaO₃, ...
- The extinction ratio can be 24.7dB

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EO Reflection Modulators



For a given input angle θ_i , the applied voltage should be

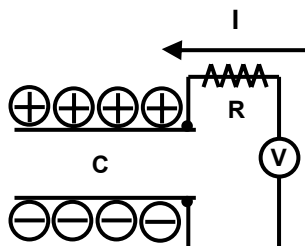
$$\left. \frac{V}{d} \right|_{TIR} = \frac{2(1 - \sin \theta_i)}{n_1^2 r_{33}} \cong \frac{1}{n_1^2 r_{33}} \left(\frac{\pi}{2} - \theta_i \right)^2$$

- High speed (6GHz) due to low device capacitance

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Figure of Merit --- $P/\Delta f$

In EO modulators, the drive power is usually consumed during state transition



The average external power P_e is defined by operating the modulator at a maximum frequency equal to its bandwidth (Δf).

$$P_e = (\Delta f) \Phi$$

Where Φ is the energy supplied from an external source to switch the modulator on or off

$$\Phi = \frac{1}{2} C V^2 \rightarrow \Phi = \frac{1}{2} \int \epsilon E_a^2 dv \quad \begin{matrix} E_a: \text{the peak amplitude of} \\ \text{the applied field} \end{matrix}$$

volume

Suppose all the electric fields are uniformly distributed in the modulator volume,

$$\Phi = \frac{\epsilon W t L E_a^2}{2}$$

W: width t: thickness L: length

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Figure of Merit --- $P/\Delta f$

Therefore, the external drive power is

$$P_e = \frac{(\Delta f) \epsilon W t L E_a^2}{2}$$

For the specific case of an EO modulator formed in GaAs, the resulting change in index of refraction are related by

$$E_a = \frac{2 \Delta n}{n_2^3 r_{41}}$$

Therefore,

$$P_e = \frac{2(\Delta f) \epsilon W t L}{n_2^6 r_{41}^2} \Delta n^2 \quad (a)$$

Suppose for a dual-channel modulator, it has shown that

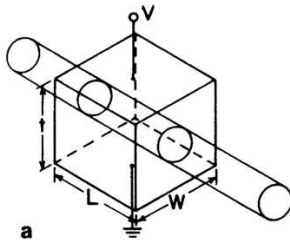
$$\Delta n_g = \frac{\sqrt{3} \pi}{k_0 L} \quad (b)$$

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Comparison of $P/\Delta f$

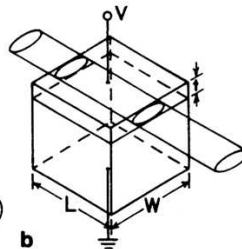
Combine (a) and (b), $\frac{P_e}{\Delta f} = \frac{3 \epsilon W t \lambda_0^2}{2 n_2^6 r_{41}^2 L}$

$$\frac{P_e}{\Delta f} \approx 148 \sim 1480 mW / MHz$$



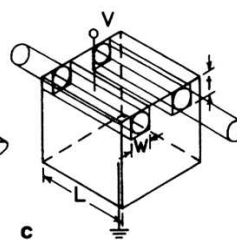
Bulk EO Modulator

$$\frac{P_e}{\Delta f} \approx 1.48 mW / MHz$$



**Planar Waveguide
EO Modulator**

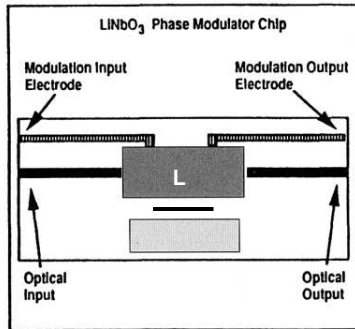
$$\frac{P_e}{\Delta f} \approx 0.148 mW / MHz$$



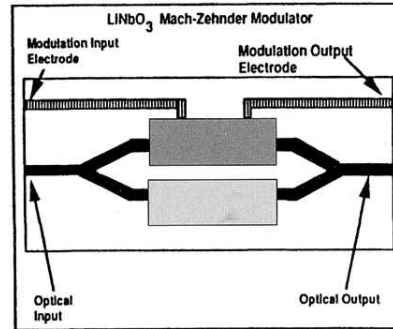
Channel EO Modulator

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Travelling Wave Electrode Configuration



a Phase Modulator



b Mach-Zehnder Modulator

- It operates at high frequency (microwave).
- The signal bandwidth is limited by the difference of microwave phase velocity (v_m) and optical wave phase velocity (v_p).

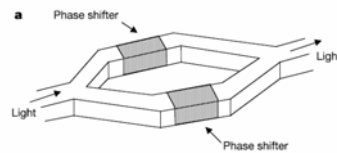
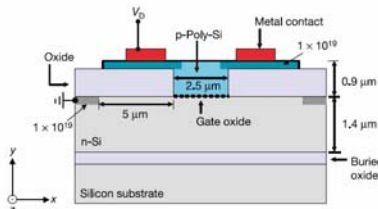
$$\frac{L}{v_p} - \frac{L}{v_m} \quad \omega_m < \frac{\pi}{2}$$

$$\omega_m \frac{L}{v_p} > \frac{\pi}{2}$$

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Silicon-based Electro-optic Device

- Free carrier plasma dispersion effect
 - Refractive index is changed by the density of free carrier
 - Ridge waveguide (Ridge part : poly-silicon, slab part : single crystal)
 - Free carrier is accumulated around the gate oxide
 - MOS Process



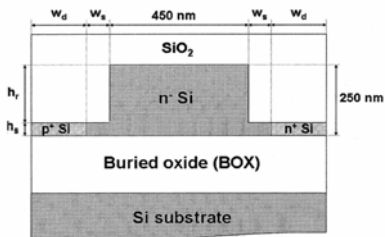
Asymmetric MZI modulator

"A high-speed silicon optical modulator based on a metal-oxide-semiconductor capacitor",
Nature '03, Ansheng Liu, Intel

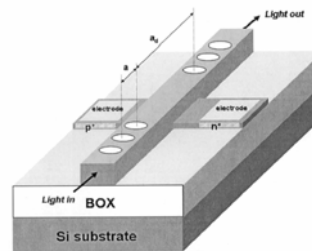
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Silicon-based Electro-optic Device

- Free Carrier Injection Effect
 - p-i-n junction around the microcavity
 - Refractive index in microcavity is changed
 - 2 distributed Bragg reflectors (DBR) are on the two sides of microcavity



Waveguide Cross Section



1D photonic crystal cavity
intensity modulator

"Electrooptic Modulation of Silicon-on-insulator Submicron-Size Waveguide device", J. of
Lightwave Tech., 2003

C. Angulo Barrios (Cornell University)

Ming-Chang Lee, *Integrated Photonic Devices*